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SLM-04300

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Jahja I. Trisnadi

Serial No.: 09/498,703

Filed: February 7, 2000

For: **METHOD AND APPARATUS FOR  
REDUCING LASER SPECKLE  
USING POLARIZATION  
AVERAGING**

) Group Art Unit: 2828

) Examiner: Armando Rodriguez

) **SUPPLEMENTAL INFORMATION**  
) **DISCLOSURE STATEMENT**

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Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313

Sir:

The citations listed below, copies attached, may be material to the examination of the above-identified application, and are therefore submitted in compliance with the duty of disclosure defined in 37 C.F.R. §§ 1.56 and 1.97. The Examiner is requested to make these citations of official record in this application.

United States Patents or Published Patent Applications have been filed electronically (EFS ID # 43749);(EFS ID #43750); (EFS ID #43751); (EFS ID #43752); (EFS ID #43753); (EFS ID #43754); (EFS ID #43755); (EFS ID #43756); (EFS ID #43757); (EFS ID #43758); (EFS ID #43759); (EFS ID #43760); (EFS ID #43762); (EFS ID #43763); (EFS ID #43764); and (EFS ID #43765).

Applicants have become aware of the following printed publication which may be material to the examination of this application:

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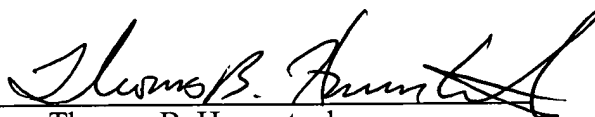
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This Supplemental Information Disclosure Statement under 37 C.F.R. §§ 1.56 and 1.97 is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that anyone or more of these citations constitutes prior art.

Respectfully submitted,  
HAVERSTOCK & OWENS LLP


Dated: 7-16-03

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Attorneys for Applicants

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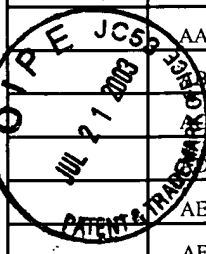
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	AG						
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**INFORMATION DISCLOSURE STATEMENT BY APPLICANT**  
(Use Several Sheets If Necessary)

Applicant: Jahja I. Trisnadi

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**FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS**

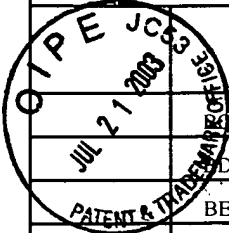
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Attorney Docket No.: SLM-04300

Serial No.: 09/498,703

**INFORMATION DISCLOSURE STATEMENT BY APPLICANT**  
(Use Several Sheets If Necessary)

Applicant: Jahja I. Trisnadi

Filing Date: February 7, 2000

Group Art Unit: 2828

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							Yes	No
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<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> (Use Several Sheets If Necessary)				Applicant: Jahja I. Trisnadi	
(37 CFR § 1.98(h))				Filing Date: February 7, 2000	Group Art Unit: 2828

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	Document Number	Publication Date	Country / Patent Office	Class	Subclass	Translation		
						Yes	No	
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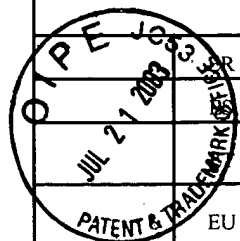
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(37 CFR § 1.98(b))

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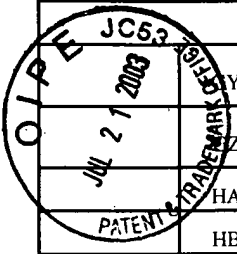
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(37 CFR § 1.98(b))

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